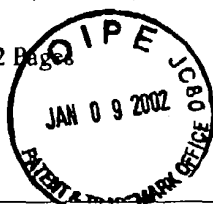


INFORMATION DISCLOSURE CITATION

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Docket: 015559-238

Serial No.: 09/833,174

Applicant: James W. Siekkinen et al.

Filed: 4/11/01

Group: 2816

U.S. PATENT DOCUMENTS

Examiner	Document No.	Date	Name	Class	Sub	
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Examiner	Document No.	Date	Country	Class	Sub		Y	N
Examiner: <u>Banera</u>		Date Considered: <u>11/28/03</u>						

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RB	Statement (including Attachments A-D).
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